

#28
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of

Group Art Unit:

Yunlong Sun and Edward J. Swenson

Application No.

Filed:

For: **LASER SYSTEM FOR FUNCTIONAL
TRIMMING OF FILMS AND DEVICES**

Date: October 28, 1997

Examiner:

PRELIMINARY AMENDMENT

TO THE ASSISTANT
COMMISSIONER FOR PATENTS:

Please amend the above-identified application as follows.

In the Specification:

Page 2, line 8, change "resistive" to --resistance--.

Page 2, line 23, change "resistive" to --resistance--.

Page 4, line 26, change "germaium" to --germanium--.

Page 4, line 27, after "either" delete "a".

In the Claims:

Amend claim 1 as follows.

1. (Amended) A laser functional trimming system for modifying with laser output a measurable operational parameter of an activated electronic device while preventing a spurious optoelectric response in the device, the device including a target material and a nontarget material positioned within optical proximity to the target material, the laser output including a laser pulse having a spatial distribution of energy that impinges the target material and exposes the nontarget material to extraneous laser output, the target material having ablation sensitivity to laser output in a first wavelength range and the nontarget material having optoelectric sensitivity to wavelengths in a second wavelength range that forms a subset of the first wavelength